



ESSENTIALS Elements

EBARA TECHNOLOGIES, INC.

News & Views • March 2018

Introducing Quiet & Ultra Compact Portable Dry Vacuum Pump EBARA's New Model EV-PA50

Ebara introduces the next generation in dry pump technology. Based on the reliable and proven design of their highly reliable and robust semiconductor pump ranges, the NEW Model EV-PA50 takes dry pumping to the next level. Its ultra-compact design with 50 l/min pumping speed makes it a perfect replacement for small wet, diaphragm and scroll pumps.

The exacting tolerances within the pump offer up to 30x better ultimate pressure than equivalent multistage diaphragm pumps improving your performance on small turbo stations and Model EV-PA50's. Repeatable vacuum performance eliminates the vacuum drift of lesser scroll technologies.



**Perfect replacement for Wet, Diaphragm
and Scroll pumps**

Maintenance free model - eliminating expensive oil changes, tip seal and diaphragm replacement.

System integrators will appreciate its 24Vdc operation and the Model EV-PA mobile with a super light design concept at less than 20lbs!

EcoQuiet operation reduces noise pollution in the lab. It's the perfect pump for mass spec users, bonders, battery manufacturing, gloveboxes, leak detectors and many more applications.

Based on Ebara's proven and reliable pumping technologies

- * 50 l/min peak speed
- * Up to 30x better ultimate vacuum than equivalent multistage diaphragm pumps
- * Improve your vacuum performance on small turbo stations
- * Repeatable Vacuum Performance
- * Maintenance Free - no more seals / diaphragms to replace or oil changes
- * Optional 24Vdc operation for easy system integration
- * Extra Quiet Operation
- * Super Light and Mobile - Less than 20lbs

**For Complete Specifications & Special Introductory Pricing
Contact your Local Ebara Representative.**

Looking ahead,
going beyond expectations

Ahead > Beyond

"Model EV-PA50" is our model code.



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NCCAUS 39th ANNUAL SYMPOSIUM & EQUIPMENT EXHIBITION

EBARA Technologies, Inc. recently exhibited at the NCCAUS 2018 Annual Equipment Exhibition on February 22nd, 2018 in San Jose, CA.



This event was held in conjunction with the NCCAUS Joint User Group Meeting & 7th Annual Student Poster Session. This year's topics included: Process, Materials, and Technology Innovations for Smart Devices, Displays, and IoT.

Ebara also welcomed a new addition to the team, Christy Kavanaugh. She has come on board as our Semiconductor Segment Manager and will be based out of our Sacramento, CA office.

GATE VALVES

Ebara Technologies Gate Valves are designed for multiple vacuum applications. Operational pressure from 10⁻⁷ Torr to 1200 Torr with maximum delta P of 1.6 atm.

These robust valves feature a smooth and shock free mechanism with an extended operational lifetime of over 100,000 cycles.

Ebara's gate valves offer minimal MTTR with easy in situ replacement of the o-rings. All versions are fitted with FKM seals as standard. Harsh duty versions are equipped with optional FFKM seals with bellows free design eliminating any potential bellows leaks from corrosive processes and operates up to 150C.

All valves are equipped with lockout tag out devices for safe operation. Position indicators are optional on manual types. Double acting pneumatic versions have a compact actuator, 24vdc/120v solenoid and position switches as standard for easy integration. Manual and pneumatic versions are available in sizes DN50, DN80, DN100, DN160.



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JOIN US AT OUR UPCOMING EVENTS



SESHA - April 17-19
Scottsdale, AZ



FL AVS - May 7-8
Orlando, FL



SVC TechCon - May 8-9
Orlando, FL



SEMICON WEST - July 10-12
San Francisco, CA